Date: June 4, 2003



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant(s)

Satoh et al.

Appl. No.

09/764,523

Filed

January 18, 2001

For

A SEMICONDUCTOR

PROCESSING DEVICE

PROVIDED WITH A REMOTE

PLASMA SOURCE FOR SELF-

CLEANING

Examiner

Rudy Zervigon

Group Art Unit:

1763

TRADEMARK OFFICE

I hereby certify that this correspondence and appropriate marked attachments are being deposited with the service as first class mail in Patents, P.O. Box 1450, Alexandria, VA 22313-1450, on

June 4, 2003

(Date)

Adeel S. Akhtar, Reg. No.

TRANSMITTAL LETTER

Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

Dear Sir:

Enclosed for filing in the above-identified application are:

- (X) A Response to Restriction Requirement.
- The Commissioner is hereby authorized to charge any additional fees which may be required, or (X) credit any overpayment, to Account No. 11-1410.
- Return prepaid postcard. (X)

Registration No. 41,394

Attorney of Record

Customer No. 20,995

(415) 954-4114



ED STATES PATENT AND TRADEMARK OFFICE

PATENT PECEIVED

EGROUP 17003 Group Art Unit 1763 **Applicant** Satoh et al. I hereby certify that this correspondence and all Appl. No. 09/764,523 marked attachments are being deposited with the United States Postal Service as first-class mail in an envelope addressed to: January 18, 2001 Filed Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450, on For A SEMICONDUCTOR June 4, 2003 (Date) PROCESSING DEVICE PROVIDED WITH A REMOTE Adeel S. Akhtar, Reg. No. 41,3 PLASMA SOURCE FOR **SELF-CLEANING** Examiner Rudy Zervigon

RESPONSE TO RESTRICTION REQUIREMENT

#96/16/03

Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

Dear Sir:

Response to Restriction Requirement

In an action mailed May 29, 2003, the Examiner required restriction of prosecution to one of the following groups of claims:

Group I Claims 41-44, drawn to a chemical vapor deposition device, classified in class

118, subclass 723ER; and

Claims 33-40, and 45, drawn to a method of cleaning a chemical vapor deposition Group II

device, classified in class 134, subclass 1.1.

Appl. No.

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January 18, 2001

In response, Applicants elect, without traverse, to proceed with examination on the merits of Group II (Claims 33-40, and 45), drawn to a method of cleaning a chemical vapor deposition device, classified in class 134, subclass 1.1.

In view of the forgoing, Applicants submit that the application is in condition for examination on the merits and respectfully request the same.

Respectfully submitted,

KNOBBE, MARTENS, OLSON & BEAR, LLP

Dated: June 4, 2003

By:

Adeel S. Akhtar Registration No. 41,394

Attorney of Record

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